Some "simple" strategies for modeling magnetically confined plasmas

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Many thanks to Lorenzo Neri, Giuseppe Castro and Federico Di Bartolo for their support in lectures preparation

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OUTLINE

1st Part

- 1. General properties of plasmas and magnetic confinement
- 2. Applications of plasma physics in the field of magnetic confinement fusion and ion sources for particles accelerators
- 3. Electron Cyclotron Resonance Ion Sources: the most performing devices for accelerator feeding with high intensity an high charge state ion beams

2nd Part

- 1. Modeling of magnetically confined plasma
- 2. Monte-Carlo code for simulation of confinement, heating, beam formation
- 3. Ray tracing calculation and balance equations
- 4. Impact of modeling on ion sources development



Plasma: the 4th state of matter



This is Plasma



Some Applications

Light (see lamps und projector)

Surface Hardening



Plasma Monitor (Television) large, well resolving, flat

Surface Refinement

Plasma treated roof of the cathedral "Christ the Saviour" in Moscow. Steel tiles covered with films of Titanium Nitride and diamond-like carbon





Main Plasma Constituents

positively charged ionselectronsneutrals

Key Plasma Properties

quasineutrality

collective behavior



Electron Temperature and Distribution Functions

Weakly ionized plasma is a mixture of different gases:

neutral gas, ion gas and electron gas.

Under the action of electromagnetic fields electrons gain much more energy from the EM-field than ions. Their mean energy exceeds by far the mean energy of the ions and the neutrals. Thus

$$T_{e} >> T_{+}, T_{n}$$

In plasma temperatures are measured in eV:

kT = 1eV corresponds to T = 11600 K

Typical values: $kT_e = 1... 10^4$ eV for electrons

kT₊ = 0.03...0.1eV for *ions*

8

Why are magnetic fields applied to plasmas?

Stabilization of electron and ion confinement is mandatory for plasma ignition or multicharged ions production

The problem of Coulomb barrier tunneling



A sufficiently high energy must be transferred to nucleons in order to lead to nuclear fusion (on the order of 10² keV). This energy corresponds to temperatures of the order of 100 million of Celsius degrees. At these temperatures the matter is PLASMA

High density – long lifetimes are required for Ion Sources also!!

$$I_{ext} \propto \frac{n_e}{\tau_i} ; \qquad < q > \propto n_e^* \tau_i$$

Plasmas at high electron density and characterized by long ion lifetimes are specifically required. They can be produced by high intensity electron beams or sustained by microwaves

Principles of magnetic confinement

Stabilization of electron and ion confinement is mandatory to achieve ignition (FUSION) or highly charged ions (INJECTORS FOR ACCELERATORS)



Gyration of ions and electrons under the action of a static magnetic field

The Lorentz force F_{L} exerted by a static magnetic field of induction *B* on particles of mass *m* bearing an elementary charge *e* causes a circular motion.

✤The radius (cyclotron radius) r_B of the circular trajectory is given by $r_B = mv/eB$

♦The corresponding cyclotron frequency $ω_B$ does not depend on the particle velocity v: $ω_B = eB/m$



14

Magnetic Confinement

Magnetic fields intrinsically force charged particles to reduce freedom degrees: electrons spiralyze around the field lines and can be trapped for several ms in mirror machines or toroidal structures.



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MIRROR STRUCTURES

have axial symmetry and can be produced by sequences of room temperature or SC coils. They are commonly used in ion sources field

TOROIDAL CONFINEMENT is typical of Fusion Machines like TOKAMAKS or STELLARATORS

The ideal confinement requires some stringent conditions on plasma equilibrium and stability

Plasma can also be viewed as fluids. Therefore the confinement and its equilibrium and stability can be investigated by looking to the equilibrium between the plasma kinetic pressure and the magnetic (confining) field pressure.

$$p + \frac{B^2}{2\mu_0} = costante$$

The stability of the confinement can be studied as a function of the β parameter, which is the ratio between the kinetic and magnetic pressures.

The condition for a magnetically stable plasma is that $\beta{<}{<}1$

 $2\mu_0$

Stability of magnetic confinement

The magneto-hydro-dynamics equation gives:

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$$\nabla p = \frac{1}{\mu_0} (\nabla \times \mathbf{B}) \times \mathbf{B} = \frac{1}{\mu_0} \left[(\mathbf{B} \cdot \nabla) \mathbf{B} - \frac{1}{2} \nabla \mathbf{B}^2 \right]$$
$$\nabla \left(p + \frac{B^2}{2\mu_0} \right) = \frac{1}{\mu_0} (\mathbf{B} \cdot \nabla) \mathbf{B}$$

In case B is smoothly variable along its own direction, the right hand term can be neglected, yielding:







Principles of magnetic mirrors

Magnetic mirrors are largely employed in ion sources field since allow the construction of compact-size machines. Some ingredients are needed to ensure efficient trapping:



 ✓ A magnetic gradient must exist along the direction of B:

$$\vec{F}_{\parallel} = -\mu \frac{\partial B}{\partial s} = -\mu \vec{\nabla}_{\parallel} B$$

$$\mu \equiv \frac{1}{2} \frac{m v_{\perp}^2}{B}$$

✓ Radial component of the magnetic field;

✓ The angle formed by the particle velocity w.r.t B must be as large as possible.

The mirror effect is a direct consequence of μ invariance.

Principles of magnetic mirrors



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$$\theta_{min} = \arcsin\sqrt{\frac{B_0}{B_m}}$$

 \checkmark Efficient confinement by a single-particle point of view.

✓Considering a fluid approach, MHD instability arises because of the bad curvature of the field lines in the midplane, causing the onset of flute instability.







ECRIS magnetic structure

The necessity of the minimum B structure





TOKAMAK-like magnetic structure



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The magnetic field inside the solenoid decreases as 1/R, where R is the main torus radius. The magnetic field is zero outside from the solenoid.

$$\mathbf{B}(R) = \mu_0 \frac{NI}{2\pi R}$$

$$\mathbf{B}(R_0) = \mu_0 \frac{NI}{2\pi R_0}$$

$$\mathbf{B}(R_0) = B_0 \frac{R_0}{R}$$

24



The B gradient induces a drift of the charged particles, which move away from the torus center:

$$\vec{V}_{DG} = \frac{\mu}{q} \frac{\vec{B} \times \vec{\nabla}B}{B^2} c$$

Being the drift due to the gradient oppositely directed for electrons and ions an electric field arises, which in turn produce an additional deconfining drift:

$$\vec{V}_{DE} = c \frac{\vec{E} \times \vec{B}}{B^2}$$

The simple toroidal field is not enough to guarantee the stable confinement of the plasma. Deriva ExB







TOKAMAK-like magnetic configuration



TOKAMAK coordinates

27



A tokamak is a machine producing a toroidal magnetic field for confining a plasma which is characterized by azimuthal (rotational) symmetry and the use of a plasma-borne electric current to generate the helical component of the magnetic field necessary for stable equilibrium.



STELLARATOR-like systems

The poloidal field is produced by additional magnets which envelope the torus. The torus is adequately twisted in order to create nested magnetic surfaces. In this case the plasma heating is not governed by inner flowing currents, but it is due to RF heating.



W7-SX Stellarator

1-helical coils, 2-toroidal field coils, 3-vertical field coils

WEGA Stellarator @ Max Planck Institute for Plasma Physics



Fundamental aspects of ion generation and ion sources

The main goal of ion sources is the production of high quality ion beams to be injected into particle accelerators, minimizing beam losses and maximizing the overall reliability

The requirements of Ion sources employed for accelerators like LINACS or Cyclotrons are:

High stability and long-time operations without significant maintenance

Production of intense beams of highly charged ions

Low emittance.

□ For pulsed operations, the number of particles per pulse must be as high as possible.



the Accelerators ones without hardware modifications

Atomic Physics background in Ion Sources Science

General Principles for the generation of multicharged ions



Atomic physics background in ECRIS Step by step ionization



The cross section for ionizing processes like $z \rightarrow z + x$ as a function of energy features a maximum value when x=1. This means that the ionization proceeds expelling one by one electrons from atomic shells.

The ionization mechanism is therefore a slow process which requires long plasma lifetime to produce highly charged ions ³⁵

Dynamical (Non-stationary)) balance equations for multi-charged ions (Shirkov 1991) dn/dt ≠ 0

$$\begin{aligned} \frac{dn_0}{dt} &= \frac{S}{V} v_0 (n - n_0) - n_0 \left(\sum_{i=2}^{z} \sigma_i^{ex} n_i v_i + \sum_{i=3}^{z} \sigma_i^{2ex} n_i v_i (\sigma_1^i + \sigma_1^{2i}) n_e v_e \right) \\ \frac{dn_1}{dt} &= n_0 \left(\sigma_1^i v_e n_e + \sigma_2^{ex} n_2 v_2 + \sigma_2^{2ex} n_3 v_3 + \sum_{i=2}^{z} \sigma_i^{ex} n_i v_i \right) \\ &- n_1 \left(\sigma_2^i v_e n_e + \sigma_2^{2i} v_e n_e + \frac{1}{\tau_1} \right) \\ - n_1 \left(\sigma_2^i v_e n_e + \sigma_2^{2i} v_e n_e + \frac{1}{\tau_1} \right) \\ \frac{dn_2}{dt} &= n_0 \left(\sigma_1^{2i} v_e n_e + \sum_{i=3}^{z} \sigma_i^{2ex} n_i v_i \right) + n_1 \sigma_2^i v_e n_e + \left(\sigma_3^{ex} n_3 v_3 + \sigma_4^{2ex} n_4 v_4 \right) n_0 \\ &- n_2 \left(\left(\sigma_1^{ex} + \sigma_1^{2i} v_e n_e + \left(\sigma_2^{ex} + \sigma_2^{2ex} \right) v_2 n_0 + \frac{1}{\tau_2} \right) \right) \\ \frac{dn_i}{dt} &= \sigma_1^i v_e n_e n_{i-1} + \sigma_{i-1}^{2i} v_e n_e + \left(\sigma_{i+1}^{ex} n_{i+1} v_{i+1} + \sigma_{i+2}^{2ex} v_{i+2} v_{i+2} \right) n_0 \\ \hline \left(\frac{3 \le i \le z - 2}{dt} \right) - n_i \left(\left(\sigma_i^{ex} + \sigma_i^{2ex} \right) v_i n_0 - \left(\sigma_{i+1}^i + \sigma_{i+2}^{2i} \right) v_e n_e + \frac{1}{\tau_{i-2}} \right) \\ \frac{dn_{i-1}}{dt} &= \left(\sigma_{i-1}^i n_{z-2} + \sigma_{z-1}^{2i} n_{z-2} \right) v_e n_e + \sigma_2^{ex} n_z v_z n_0 \\ &- n_{z-1} \left(\sigma_2^i v_e n_e + \left(\sigma_{z+1}^{ex} + \sigma_{z+1}^{2ex} \right) v_{z-1} n_0 + \frac{1}{\tau_{i-1}} \right) \\ \frac{dn_x}{dt} &= \left(\sigma_x^i n_{z-1} + \sigma_{z-1}^{2i} n_{z-2} \right) v_e n_e - n_x \left(\left(\sigma_x^{ex} + \sigma_z^{2ex} \right) v_z n_0 + \frac{1}{\tau_{z-1}} \right) \\ \sigma_i^{ex} and \sigma_i^{2ex} = single - and double - charge \\ &- exchange cross sections of the ions with charge state i \\ \sigma_i^i and \sigma_i^{2i} = single - and double \\ &- ionization cross sections of the ions with charge state i - 1 \\ \end{array} \right)$$


Four types of ion sources for multicharged ions production or single-charged intense ion beams

EBIS (Electron Beam Ion Sources): easy production of beams at high charge states (very long plasma lifetime), unavailable for high intensity single charge ion beams (too long plasma lifetime)

MDIS (Microwave Discharge Ion Sources): simplified version of ECRIS for high intensity proton (or single charge state ions) beams. **BEST COMPROMISE** for production of intense beams of highly charged ions

LIS (Laser Ion Sources): intense beams of medium and high charge states, production of metallic ions from refractive materials, but unable to produce beams in CW mode ECRIS (Electron Cyclotron Resonance Ion Sources): intense beams of low charge states, moderate intensity of highly charged ions











The cutoff density

$$\epsilon(\omega) \sim 1 - \frac{\omega_p^2}{\omega^2}$$

The propagation of e.m. waves is possible if $\epsilon > 0$

$$\omega_p^2 = \frac{4\pi n_e e^2}{m_e}$$

The plasma frequency is connected to self-generated plasma oscillations which strongly affect the wave propagation.

Above the cutoff the wave cannot propagate:

$$n_{cutoff} = 4\pi^2 \frac{m\epsilon_0}{e^2} f_p^2$$

44

I N F N **ECRIS Standard Model** Scaling Laws (R. Geller-1987): 1. We have to increase the Microwave frequency to attain higher electron densities For many years they represented the guideline for ECRIS development 2. No considerations about the $I \propto \frac{\omega_{RF}^2}{M} \qquad \langle q \rangle \propto \log \omega_{RF}^{3.5}$ confinement High-B Mode (G. Ciavola-S.Gammino, 1990) High mirror rations ensure the MHD stability exploiting the density increase. It doesn't conflict with Scaling Laws, but it limits their efficiency to high confined plasmas B>4T for future ECRIS ! ->2 B_{ECR}



Plasma Heating

Modeling electron heating driven by microwaves









This formula accounts for the composition of the bouncing and cyclotron frequencies, leading to an effective multi-waves interaction



[Lieberman&Lichtenberg, Plasma Phys. 15 125 (1973); A. Girard et al. Phys Rev E]



Unexplained experimental results

Models are in qualitative agreement with experiments as concerns the large frequency and B field variation, but they do not explain extreme sensitivity of X-ray production to slight L adjustments, or output currents and emittance dependence on the fine frequency tuning



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How does the pumping wave frequency influence the plasma heating?





Comparison between trends of O^{8+} at 18 *GHz* for klystron (up to 800 W) and TWT1 operating in the same range of frequency.

TWT worked better than klystron: why?







Numerical Approaches for palsma modeling in Ion Sources

- RF coupling
- Single particle kinetics
- Self-consistent strategies
- Propagation of electromagnetic waves
- Extraction
- Transport

Montecarlo code for plasma Simulation

A new 3D code for calculation of particles trajectories, density and energy distribution, trapping efficiency and direct ECR-heating

Advantages

- Single particle calculation
- Simulation of collisions and prediction on average particles lifetime
- Simple tuning of parameters

Limitations

- No evidences of fluid instabilities
- Difficult feedback evaluation on waves dynamics
- Parameterized calculation of charge state distribution

"Physics" included into the equations

- External Magnetic Filed;
- Relativistic electron mass variation;
- RF power source (resonant cavity model);
- Physical plasma chamber walls (total absorption model);
- Electrostatic (Spitzer) collisions at 90°;
- Particle tracing and accumulation of density in 3D grid

Simulation of stationary system

Simulation of Simeto river

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1° Simulation of all involved particles + Continuous creation and

destruction of particles

2° Simulation of well defined statistical sample + Accumulation and statistical information for all the life of the sample











Code's structure for solving the single particle equation of motion tspan=0:Tstep:Tstep*(double(nPunti)-1); % fixes temporal domain options=odeset('RelTol', 1e-7, 'Events', @eventStop); % relative error tolerance and "events" routine for stopping integration when some conditions are valid (particle deconfinement) [t,X]=ode45(@functionSimulazioneECRH,tspan,X0(:),options); %ODE solver in t interval, with X0 array of initial conditions X0=[X Y Z normrnd(0, sigma, 1, 3)]; % array of initial conditionsc Routine for extraction of three random number from three normal distributions having a given σ and μ function [value,isterminal,direction]=eventStop(t1,x,t2,t3,t4) cond $x=sqrt(x(1)^{2}+x(2)^{2})-0.032;$ cond z=abs(x(3))-0.10;value=cond x*cond z; % event function isterminal=1;%Stop the integration when the particle reach the plasma chamber walls.

direction=0; Stop the integration when the zero crossing occurs from every direction.



Ordinary Differential Equations (ODE) solver in MATLAB

			Best	compron	nise as cono	cern rapidity of
Parameters	ode45	calculation and error tolerance.				
RelTol, AbsTol, NormControl	\checkmark	Numerical error setting	Solver	Problem Type	Order of Accuracy	When to Use
OutputFcn, OutputSel,	\checkmark	Helps in fixing boundaries for trapping Refine and fixes integration steps	ode45	Nonstiff	Medium	Most of the time. This should be the first solver you try.
Refine, Stats NonNegative	√		ode23	Nonstiff	Low	For problems with crude error tolerances or for solving moderately stiff problems.
Events MaxStep, InitialStep	$\frac{\sqrt{1-\frac{1}{2}}}{\sqrt{1-\frac{1}{2}}}$		ode113	Nonstiff	Low to high	For problems with stringent error tolerances or for solving computationally intensive problems.
Jacobian, JPattern,	_	-	ode15s	Stiff	Low to medium	If ode45 is slow because the problem is stiff.
Vectorized Mass MStateDependence	 √		ode23s	Stiff	Low	If using crude error tolerances to solve stiff systems and the mass matrix is constant.
MvPattern MassSingular			ode23t	Moderately Stiff	Low	For moderately stiff problems if you need a solution without numerical damping.
InitialSlope MaxOrder, BDF	_ _		ode23tb	Stiff	Low	If using crude error tolerances to solve stiff systems.

$$B_{x} = -B_{1}xz + 2Sxy$$

$$B_{y} = -B_{1}yz + 2S(x^{2} - y^{2})$$

$$Bz = -B_{0} + B_{1}z^{2}$$
Terms for longitudinal trap asymmetrization
$$\int_{\substack{f x(3) < 0 \\ B1 = 64.5; \\ else \\ B2 = 0.387; \\ B1 = 57; \\ end
}$$

$$\int_{\substack{s=1100; \\ Bx = B1.*x(3).*x(3) + 2*5.*x(1).*x(2); \\ Bx = B1.*x(3).*x(3) + 5.*x(1).*x(2); \\ Bz = B1.*x(3).*x(3) + 5.*x(1).*x(2):x(3) + 5.*x(1).*x(2); \\ Bz = B1.*x(3).*x(3) + 5.*x(1).*x(2):x(3) + 5.*x(1).*x(2):x(3) + 5.*x(1) + 5.*x(1).*x(2):x(3) + 5.*x(1).*x(3) + 5.*x(1).*$$







Resonant Absorption of Electromagnetic Waves




Resonant Absorption of Electromagnetic Waves

The simplified version of the equation of motion provides the analytical solution for electron velocity when resonance conditions are fulfilled

$$m_e \frac{d\vec{v}}{dt} = q_e \vec{E} - m_e \vec{v} \omega_{eff} + q_e \vec{v} \times \vec{B}_0$$

 $|v_x|^2 = \frac{q_e^2}{m_e^2} A^2 \frac{\omega_{eff}^2 + (\omega + \omega_g)^2}{(\omega_g^2 - \omega^2 + \omega_{eff}^2)^2 + 4\omega^2 \omega_{eff}^2}$ $|v_y|^2 = \frac{q_e^2}{\omega_g^2} A^2 \frac{\omega_{eff}^2 + (\omega + \omega_g)^2}{(\omega_g^2 - \omega^2 + \omega_{eff}^2)^2 + 4\omega^2 \omega_{eff}^2}$ Circular polarization DX:

Circular polarization

SX:

$$\begin{aligned} & m_e^{2^{-r}} (\omega_g^2 - \omega^2 + \omega_{eff}^2)^2 + 4\omega^2 \omega_{eff}^2 \\ & \mathsf{F}(\omega) \\ & |v_x|^2 = \frac{q_e^2}{m_e^2} B^2 \frac{\omega_{eff}^2 + (\omega - \omega_g)^2}{(\omega_g^2 - \omega^2 + \omega_{eff}^2)^2 + 4\omega^2 \omega_{eff}^2} \\ & |v_y|^2 = \frac{q_e^2}{m_e^2} B^2 \frac{\omega_{eff}^2 + (\omega - \omega_g)^2}{(\omega_g^2 - \omega^2 + \omega_{eff}^2)^2 + 4\omega^2 \omega_{eff}^2} \end{aligned}$$



Resonant Absorption of Electromagnetic Waves

Electron velocity for the R wave

Trend of $F(\omega)$ as a function of ω/ω_g :



Resonance (a) $\omega = \omega_{q}$ Electron energy

increase due to resonant interaction with the magnetic field









Theoretical determination of the modes distribution

TM modes in vacuum

TE modes in vacuum



 $FWHM = \frac{f_{nv} r}{r}$

 Q_0

 $f_{nv r} = \frac{c}{2\pi} \sqrt{\left(\frac{x'_{nv}}{\frac{1}{2}}\right)^2} + \left(\frac{r\pi}{\frac{1}{2}}\right)^2}$

78



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Numerical approach for calculating the caivty EM field

HFSSTM

- Based on the Finite Element Method
- •It is indicated for efficient simulation of cilindrical objects
- •It discretizes the calculation domain into tetraedrons
- •By using the PML boundary conditions, it supports eigenmode simulation of partially open structures.

CST Microwave Studio™

- •Based on the Finite Integration Technique, working on time domain
- •It is indicated for efficient simulation of cylindrical objects
- It doesn't support the eigenmode simulation of partially open structures





```
%autovalore modo TE 4,4,23
h=x n ni/a;
rho=sqrt(x(1).^{2+x}(2).^{2};
arg bessel=h.*rho;
                                                      %argomento funzioni di bessel per
  il modo TE 4,4,23
phi var=atan(x(2)./x(1));
freqRF=(c/(2*pi))*sqrt((x n ni/a)^2+((r*pi)/l)^2); %frequenza di risonanza per il
   modo TE 4,4,23
omegaRF=2*pi*fregRF;
%% definisco la derivata prima della funzione di bessel corrispondente al modo
   eccitato
global BesseljMap4 BesseljMap5
Bj=BesseljMap4(int32(arg bessel*1e5));
bessel der=(n./arg bessel).*Bj-BesseljMap5(int32(arg bessel*1e5));
% componenti dei campi elettrico e magnetico associati all'onda e.m.
                                                      % permeabilità magnetica del
mu 0=4*pi*1e-7;
  % equazioni dei campi relative al modo TE 4,4,23
Ex em=((mu 0*omegaRF)/h).*sin((r*pi.*x(3))./l).*Amplitude.*((n./
   (h.*rho)).*Bj.*sin(n.*phi var).*cos(phi var)-
   bessel der.*cos(n.*phi var).*sin(phi var)).*cos(omegaRF*t);
Ey em=((mu 0*omegaRF)/h).\overline{*}sin((r*pi.*x(\overline{3}))./l).*Amplitude.*((n./
   (h.*rho)).*Bj.*sin(n.*phi var).*sin(phi var)
   +bessel der.*cos(n.*phi var).*cos(phi var)).*cos(omegaRF*t);
Bx em=-((mu 0*r*pi)/(l*h)).*cos((r*pi.*x(3))./l).*Amplitude.*((n./
```

Electromagnetic Field





Dominant collisions



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The most common collisions in fully ionized – hot plasmas are the multi-electrostatic, Spitzer collisions with a total scattering angle of 90°

e-e/i-i ("like particles" scattering) collisions dominate over e-i/i-e collisions ("unlike particles" scattering) $\tau_m^{ee} \sim \tau_{90^\circ}^{ee} \text{ and } \tau_m^{ei} \gg \tau_{90^\circ}^{ei}$

 $\begin{aligned} \mathbf{f}_{90^{\circ}} &= \frac{1}{\tau_{sp}} = 5 \cdot 10^{-6} n \frac{\ln\left(\frac{\Lambda_D}{b}\right)}{T_e^{\frac{3}{2}}} \\ \nu_{90^{\circ}}^{ei} &= \frac{1}{\tau_{sp}} \sim 2 \cdot 10^{-6} z n \frac{\ln\left(\frac{\Lambda_D}{b}\right)}{T_e^{\frac{3}{2}}} \\ \nu_{90^{\circ}}^{ii} &= \frac{1}{\tau_{sp}} \sim z^4 \left(\frac{m_e}{m_i}\right)^{\frac{1}{2}} \left(\frac{T_e}{T_i}\right)^{\frac{3}{2}} \nu_{90^{\circ}}^{ee} \end{aligned}$ Caracteristic caracteristic caracteristic caracteristic time $\begin{cases} \tau_m^{ee} ~\sim~ \tau_{90^\circ}^{ee} \sim \tau_{90^\circ}^{ei} \\ \tau_m^{ii} ~\sim~ \tau_{90^\circ}^{ii} \sim \left(\frac{m_i}{m_e}\right)^{\frac{1}{2}} \tau_{90^\circ}^{ei} \\ \tau_m^{ei} ~\sim~ \tau_m^{ie} \sim \frac{m_i}{m_e} \tau_{90^\circ}^{ei} \end{cases}$

86



Dominant collisions

Numerical technique for single particle 90° collisions

- 1. The most probable collision type are the electrostatic i-i and e-e multiple collisions with velocity rotation of 90°
- 2. Collision position is determined by comparing a randomly extracted number in the range 0-1 with the collision probability

$$(0 < rnd < 1) < P(t) = 1 - \exp\left(-\frac{t}{\tau_{coll}}\frac{1}{\dot{J}}\right)$$

The collision time is given by:

 $\tau_{coll} = \frac{M_{i,e}^2 2\pi \varepsilon_0^2 v_{i,e}^3}{n_e z^4 e^4 \ln \Lambda}$ Where the plasma density is an input parameter

$$n_{ECRIS}(x, y, z) = 0.3n_{cutoff} + \sum_{i} hn_{cutoff} \exp\left\{-\frac{\left[B_{tot}(x, y, z) - (B_{ECR} - ki)\right]^2}{k^2}\right\}$$

This formula is the initial parameterization of plasma distribution (preliminary 2D PIC simulations were used)







Electron Resonant acceleration

$$\vec{E} = \hat{x}E_0 \cos\left(\frac{\omega}{c}z - \omega t + \phi\right)$$
$$\vec{H} = \hat{y}\frac{E_0}{\mu c}\cos\left(\frac{\omega}{c}z - \omega t + \phi\right)$$

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The energy exchange depends on the wave-toelectron phase relationship.

> ECR zone crossing; the resonance takes place only where B=BECR

Electron acceleration proceeds in a timescale of 1-2 nsec















Confinement parameter

 $\frac{1}{\sqrt{2}} \frac{B_{\text{max}}}{B}$

93











Self-consistency implementation

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Simplified ray tracing

A first way to get self-consistency





Simulating the Ray propagation in plasma

The angle at iteration **i** depends on the angle at iteration **i** -1 by means of the Snell laws $\sin \vartheta(\mathbf{i}) \times \mathbf{n}(\mathbf{i}) = \sin \vartheta(\mathbf{i}-1) \times \mathbf{n}(\mathbf{i}-1)$

Where **n(i)** is the refraction index of the medium:

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 $\mathbf{n}^{2} = 1 - \frac{2X(1-X)}{2(1-X)Y^{2}\sin^{2}(\vartheta) \pm \left[Y^{4}\sin^{4}(\vartheta) + 4(1-X)^{2}Y^{2}\cos^{2}(\vartheta)\right]^{\frac{1}{2}}}$



density

Appleton-Hartree formula for the anisotropic plasma refraction index

Normalized magnetic field

X and Y **depend on the electron density of the plasma** at position i and on magnetic field on position i

Preformed electron density and magnetic field maps are needed!!







Case 2: Plasma filled cavities

In plasma filled cavities the microwaves are absorbed at the resonances and reflected at cut-off surfaces, depending on the value of electron density and magnetic field:

Resonance condition:

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Reflection condition:

n < 0

$$\cos^{-1}\left(\frac{\mathbf{X} + \mathbf{Y}^2 - 1}{XY^2}\right)^{\frac{1}{2}} = 0$$

It's not so simple to solve the problem for reflection. It's necessary to valuate the surface of reflection.

The numerical method allows to find regions in which the resonance occurs



Importance of Modeling

Explanation of the impact of magnetic field and pumping wave frequency on ion and electron dynamics
FINE TUNING OF ECRIS PARAMETERS (B, f)

How does the pumping wave frequency influence the plasma heating?











Profile of electron density for the different energy domains

<100 eV

10²-10³ eV

10³-10⁴ eV

−>5·10⁴ eV ■ total density

 10^{4} -5·10⁴ eV



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The simulated structure of the electron density provides information on:

 Regions of ion generation

 Properties of plasma heating

 Mechanisms of plasma confinement

Strongly non-homogeneous distribution of the electrons inside the plasma chamber due to the action of the electromagnetic wave through ECR

114



[D. Mascali, K. Wiesemann, L. Neri L. Celona, S. Gammino and G. Ciavola, in preparation for Phys. Rev. E]

Explanation of plasma plugging inside the plasmoid

INFN



Towards self-consistency: ion formation

Ions initial position can be extracted where high energy electrons are placed. Net ionelectron density determines fluctuations in plasma quasi-neutrality (first step towards self-consistency).

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Huge impact of FTE on ion dynamics and beam formation

Jyvaskyla ECRIS

INFN



GSI-ECRIS (CAPRICE)



Hollow beam formation is a common feature of most of ECRIS.

Transversal beam shape confirms ions are magnetized in outer plasmoid region

Near axis density depletion takes place because of low FM field. Most of the resonant modes at f>10GHz exhibit holes in near axis zone 0.2 -1 0.1 -0.06 Π 0.04 -0.1 -0.02 -0.2 -0.05 -0.02 Ο -0.04 120 -0.06 -0.05



Preliminary results on self-consistent lon Dynamics Corrugation of the primary plasma surface

At first approximation it was assumed to be the same of the electromagnetic field pattern

[D. Mascali et al. *Plasma ion dynamics and beam formation in Electron Cyclotron Resonance Ion Sources*, Rev. Sci. Instrum.]



Simulated Ar¹⁰⁺ Smooth primary plasma surface 30 V of PP-SP electrostatic potential Simulated Ar¹⁰⁺ "Corrugated" primary plasma surface 30 V of mean PP-SP potential

Ion lifetime depends strongly on corrugation, mean value of accelerating potential and inner resonance plasma density. Recent simulations estimate $\tau_i \sim 0.5$ -3 ms, according to density fluctuations.

Thank you for your attention!!

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